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DE LA RECHERCHE À L'INDUSTRIE



Near-field laser ablation for surface nano-analysis: modeling and experiments

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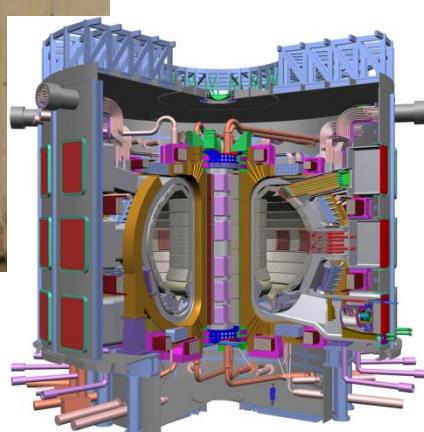
⁴ SPEC, CNRS, CEA, Université Paris-Saclay, F-91191, Gif sur Yvette, France

FLAMN-2019, Saint Petersburg, Russia 01 - 04 July, 2019

Development of innovative laser methods in DEN/DANS/DPC/SEARS CEA Saclay

- **Surface Cleaning and Decontamination:**

- paint on concrete;
- metals;
- laser detritiation for ITER (heating and ablation);



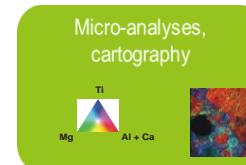
- **Surface Improvement and Micro-Processing:**

- material durability by rapid laser heating (corrosion resistance);
- laser projection of powder (3D-printing);
- micro-gravure (micro-systems);



- **Analytical Methods:**

- LIBS (elemental bulk- and μ -analysis):
 - ✓ in nuclear environment (portable LIBS);
 - ✓ in situ purity control of liquid sodium;
 - ✓ on-line analysis of liquid glasses (wastes);
 - ✓ elemental μ -cartography;
- ChemCam for the Mars exploration;
- Active laser pyrometry (layer thickness, resistance, conductivity, etc);
- Lock-in Thermography for characterization of nuclear materials;
- **Near-Field Laser Ablation – ICP MS**



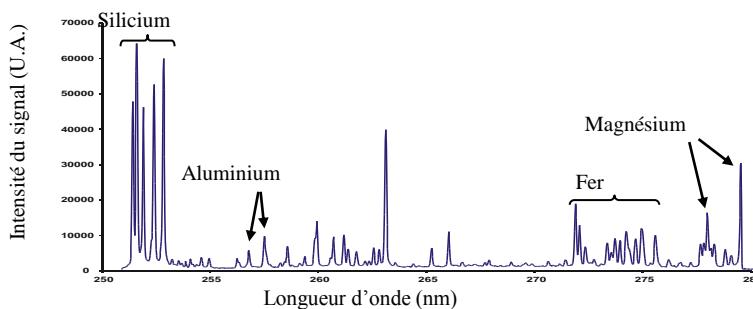
Surface Cartography

Surface cartography with micrometric
and nanometric resolution

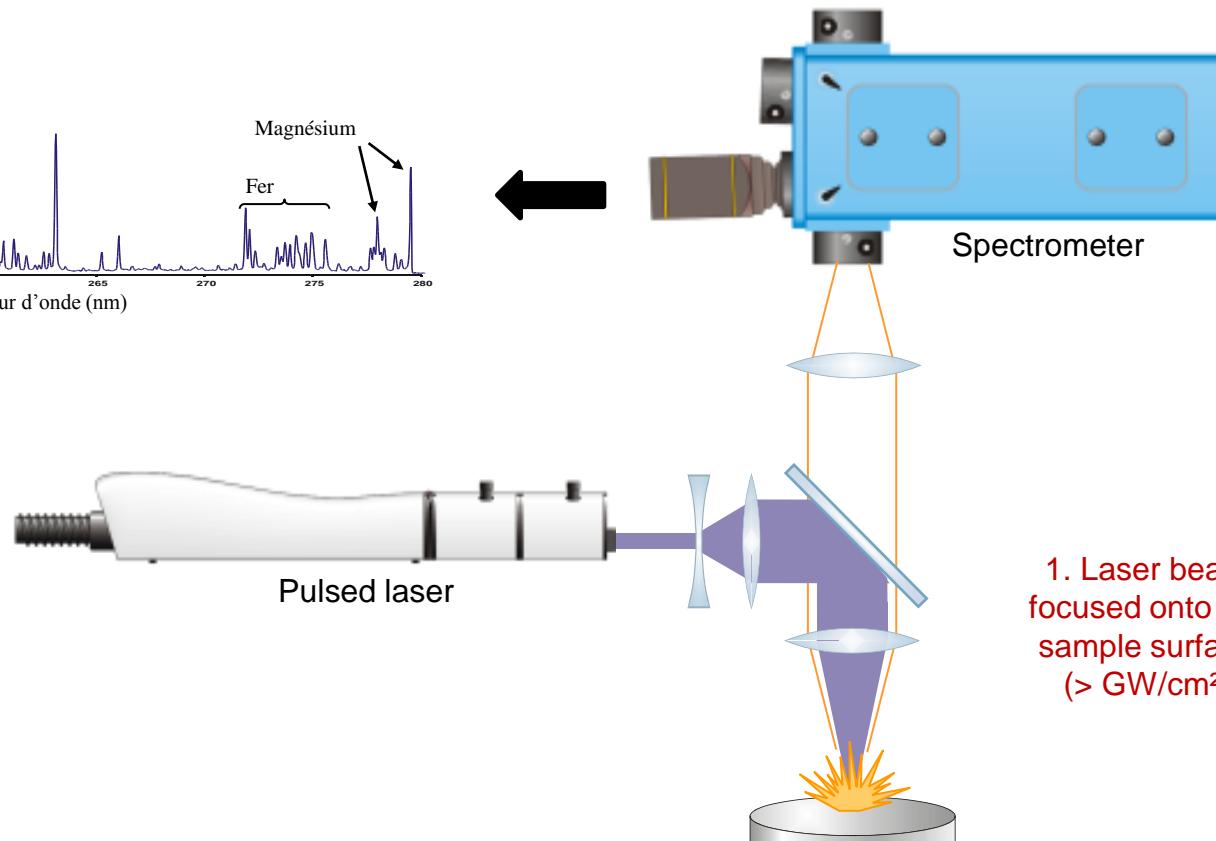
(elemental and isotopic analysis)

Micro-LIBS

4. Identification and quantification of elements



3. Plasma emission spectrum recording

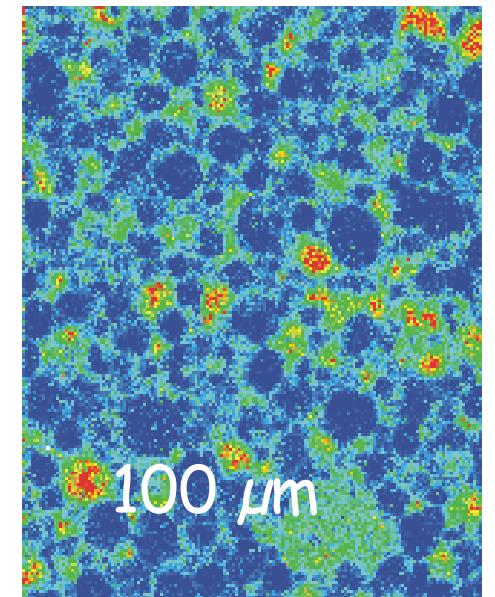


1. Laser beam focused onto the sample surface ($> \text{GW/cm}^2$)

2. Evaporation and plasma formation

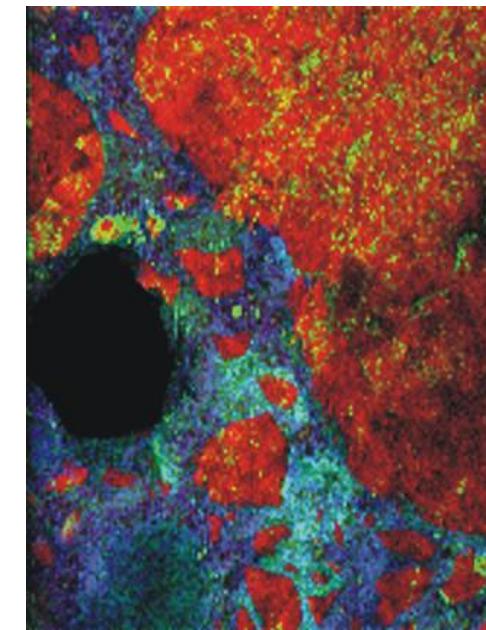
Surface cartography (1-10 μm resolution)

MOX pellet



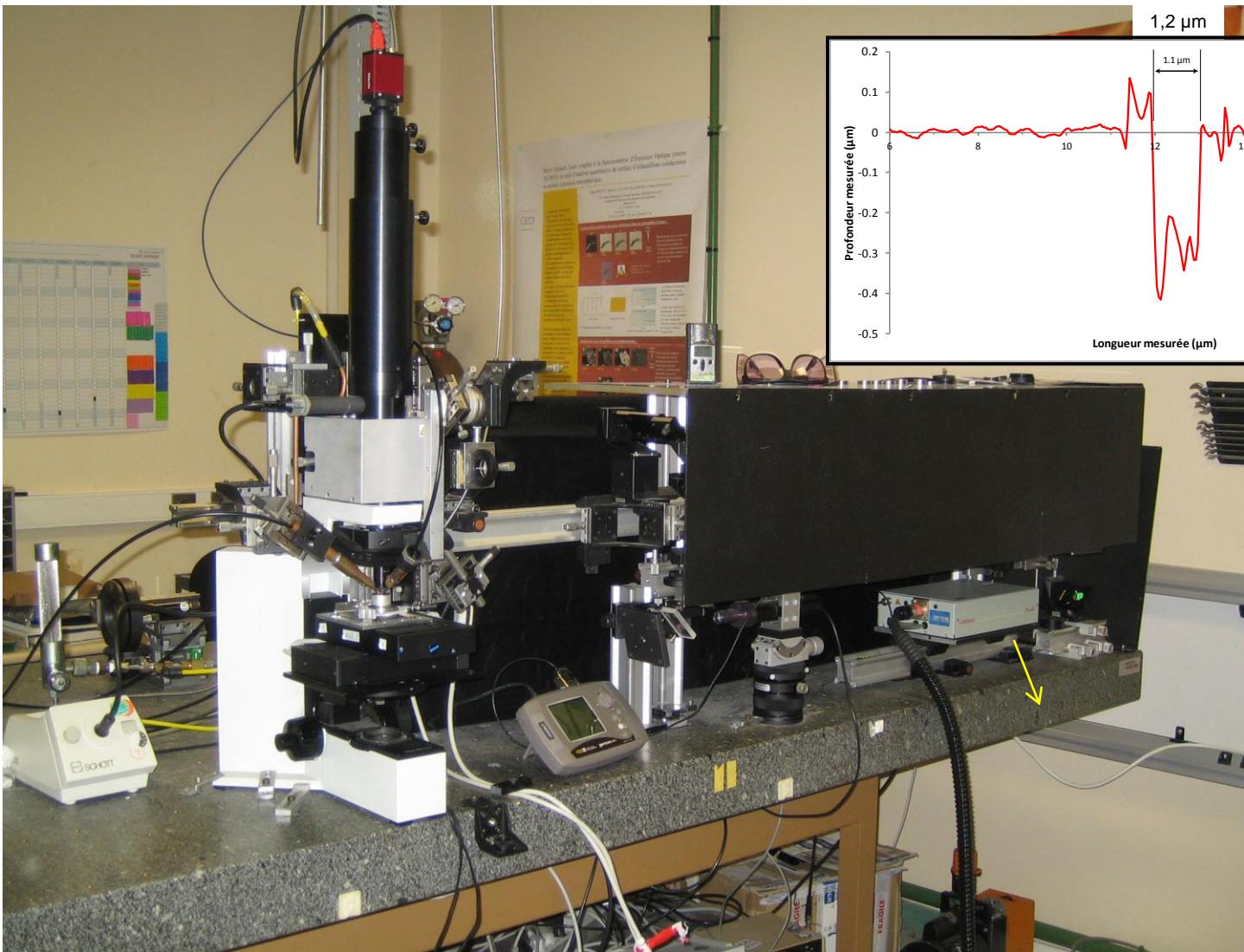
0% [Ce] 40%

Concrete



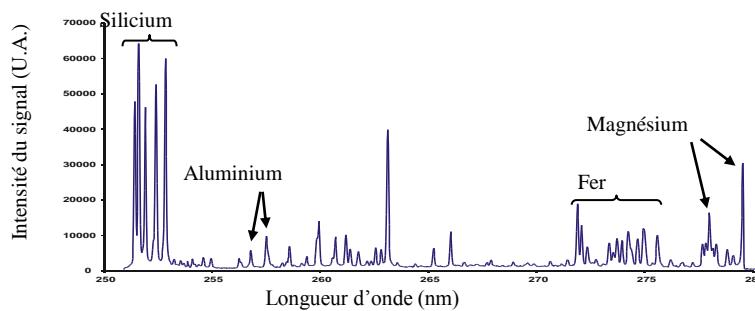
Ti
Mg Al + Ca

CEA Saclay micro-LIBS

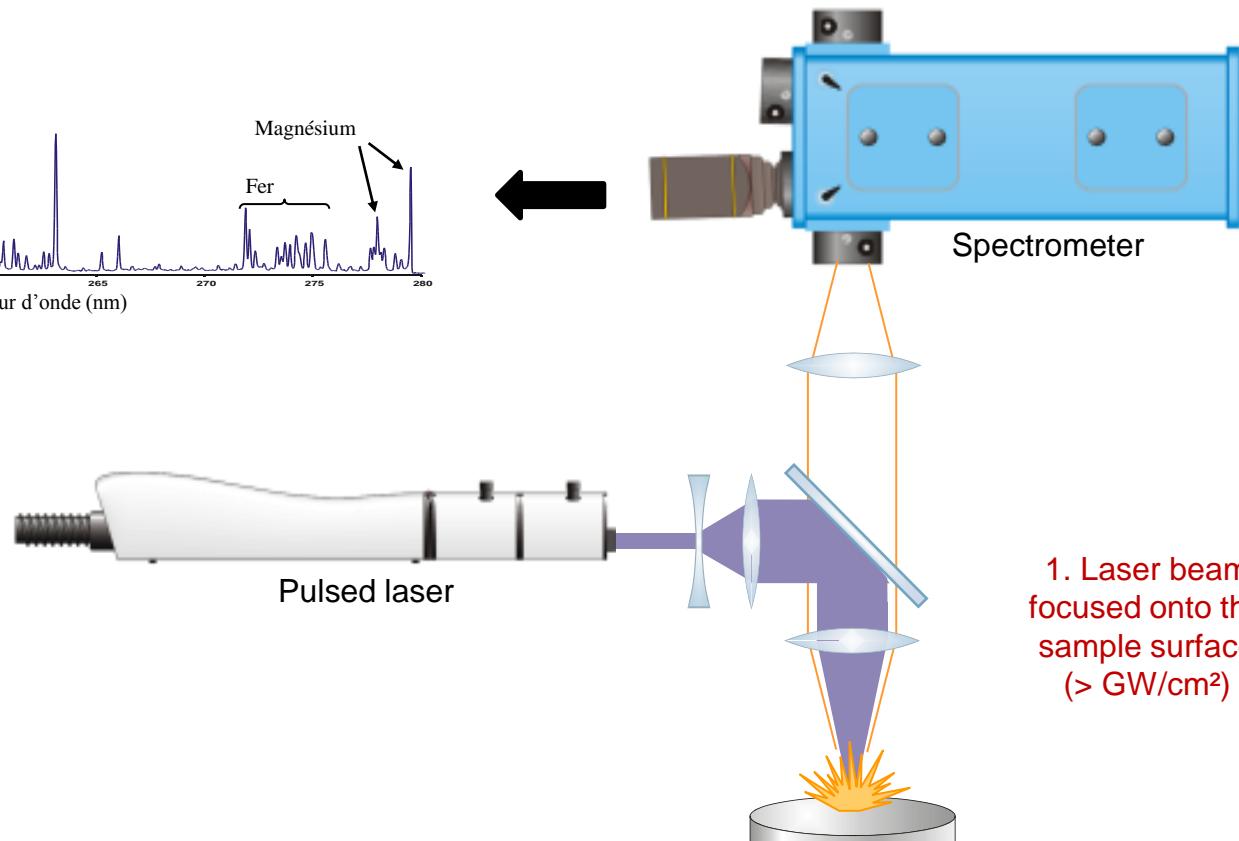


Micro-LIBS

4. Identification and quantification of elements

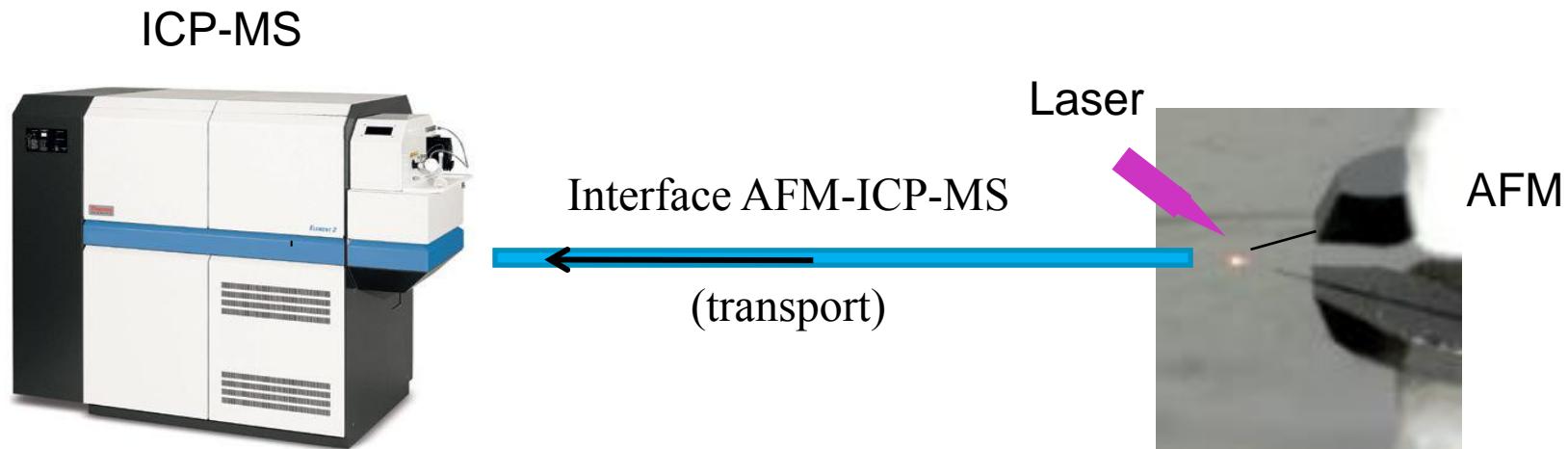


3. Plasma emission spectrum recording



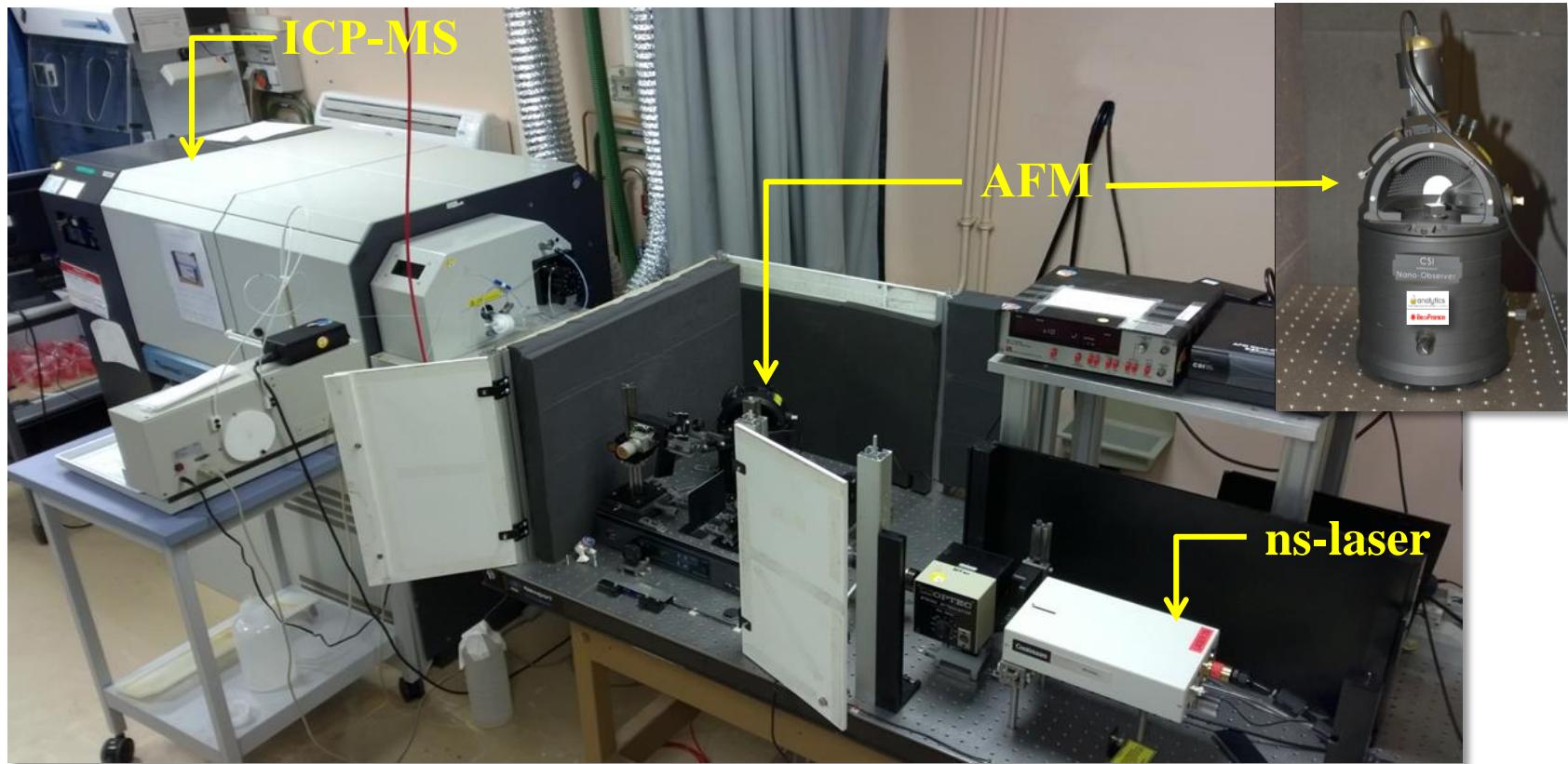
Surface cartography (10-100 nm resolution)

AFM-ICP-MS development



- 1. Near-field enhancement**
- 2. Near-field laser ablation**
3. Ablated matter transport to ICP-MS
4. MS-detection

Experimental installation

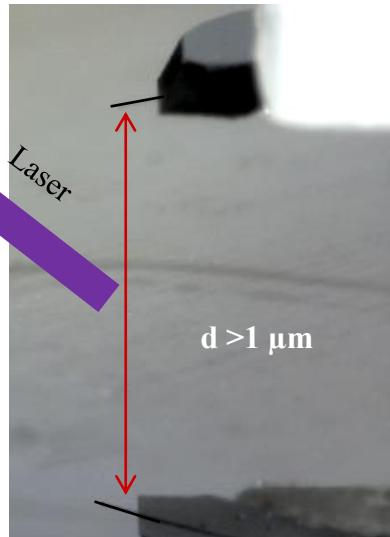


Laser Nd:YAG (266 nm) , 4 ns pulse duration.

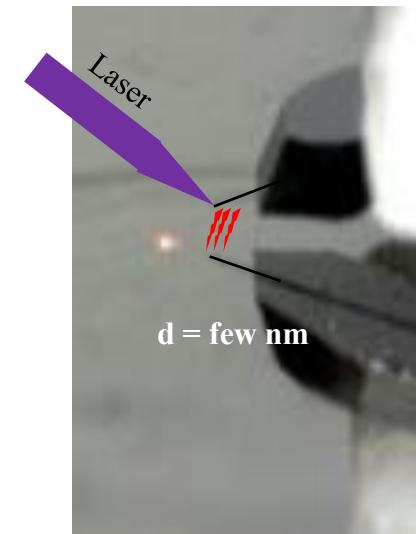
AFM: Atomic Force Microscope.

ICP-MS: Inductively Coupled Plasma - Mass Spectrometry : double-focusing sector field

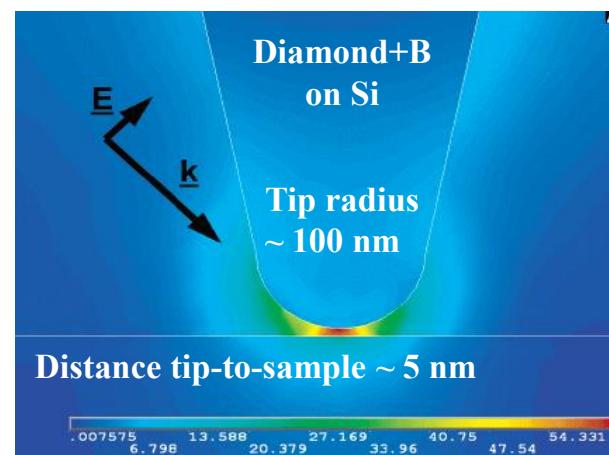
Near-field Laser Ablation



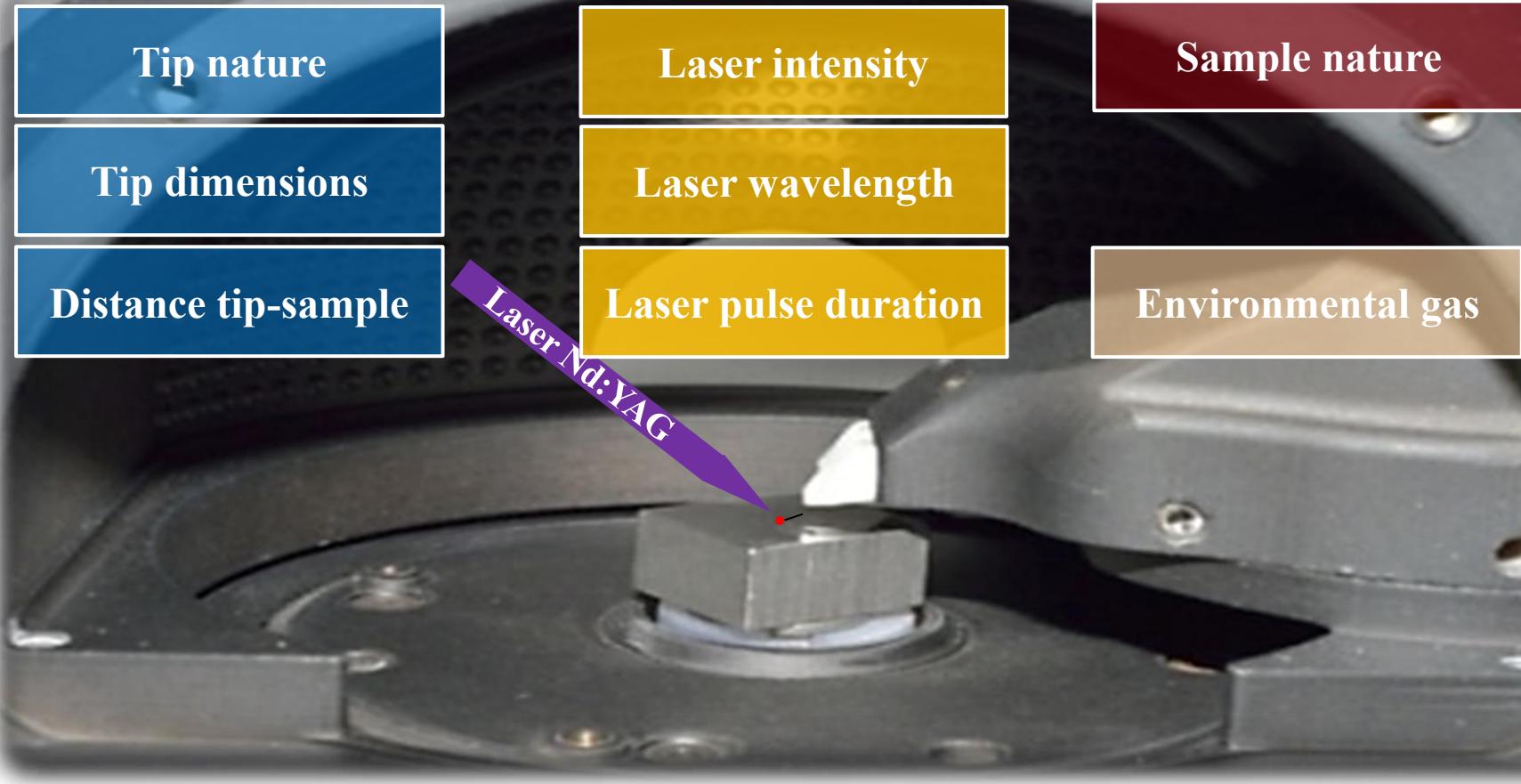
**No tip enhancement effect
(no ablation)**



**Laser energy enhancement
(near-field ablation)**



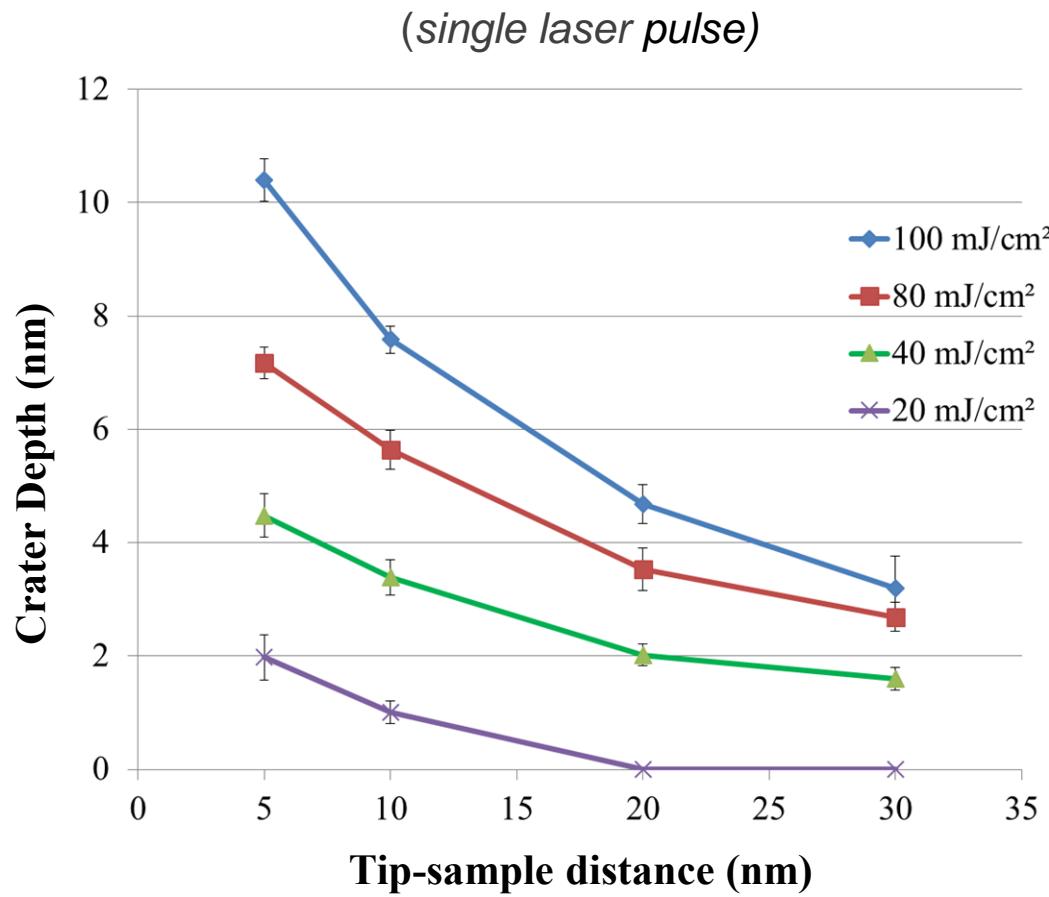
Multi-parametric study



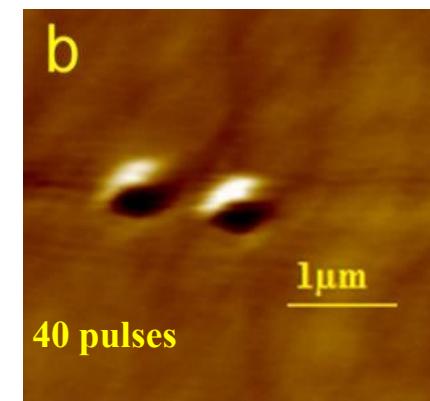
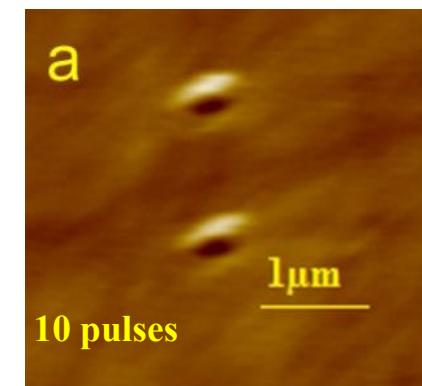
Parameters affecting the near-field ablation efficiency
and craters dimensions (ablated mass amount)

Experimental results (with Au)

Tip-sample distance and laser irradiance effects on the craters dimensions



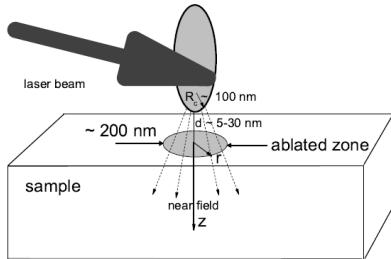
$\lambda_{laser} = 266 \text{ nm}$, $\tau = 4 \text{ ns}$, 80 mJ/cm^2 ,
Tip-sample distance: 5 nm



Sampling mass ~ 1 fg / pulse

Modeling of near-field distribution and ablation

$$I_{NF}(x, y, z, t) \Rightarrow T_{\text{Sample}}(x, y, z, t) \Rightarrow \text{ablation rate}$$



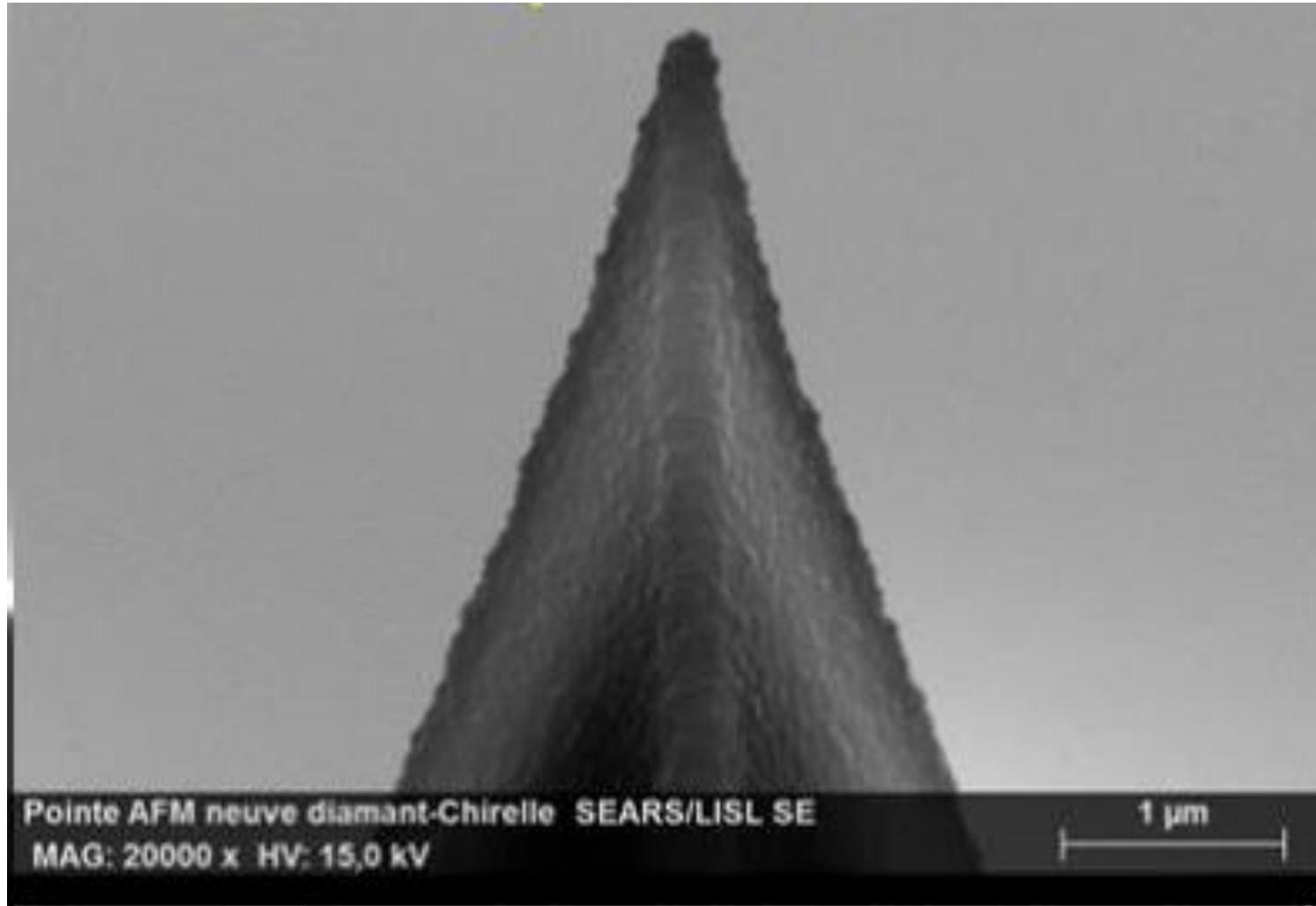
Two-temperature model

$$\begin{aligned} c_e \frac{\partial T_e}{\partial t} &= \operatorname{div}\left(k_e \nabla T_e\right) - \beta(T_e - T_i) + Q \\ c_i \frac{\partial T_i}{\partial t} &= \operatorname{div}\left(k_i \nabla T_i\right) + \beta(T_e - T_i) \end{aligned}$$

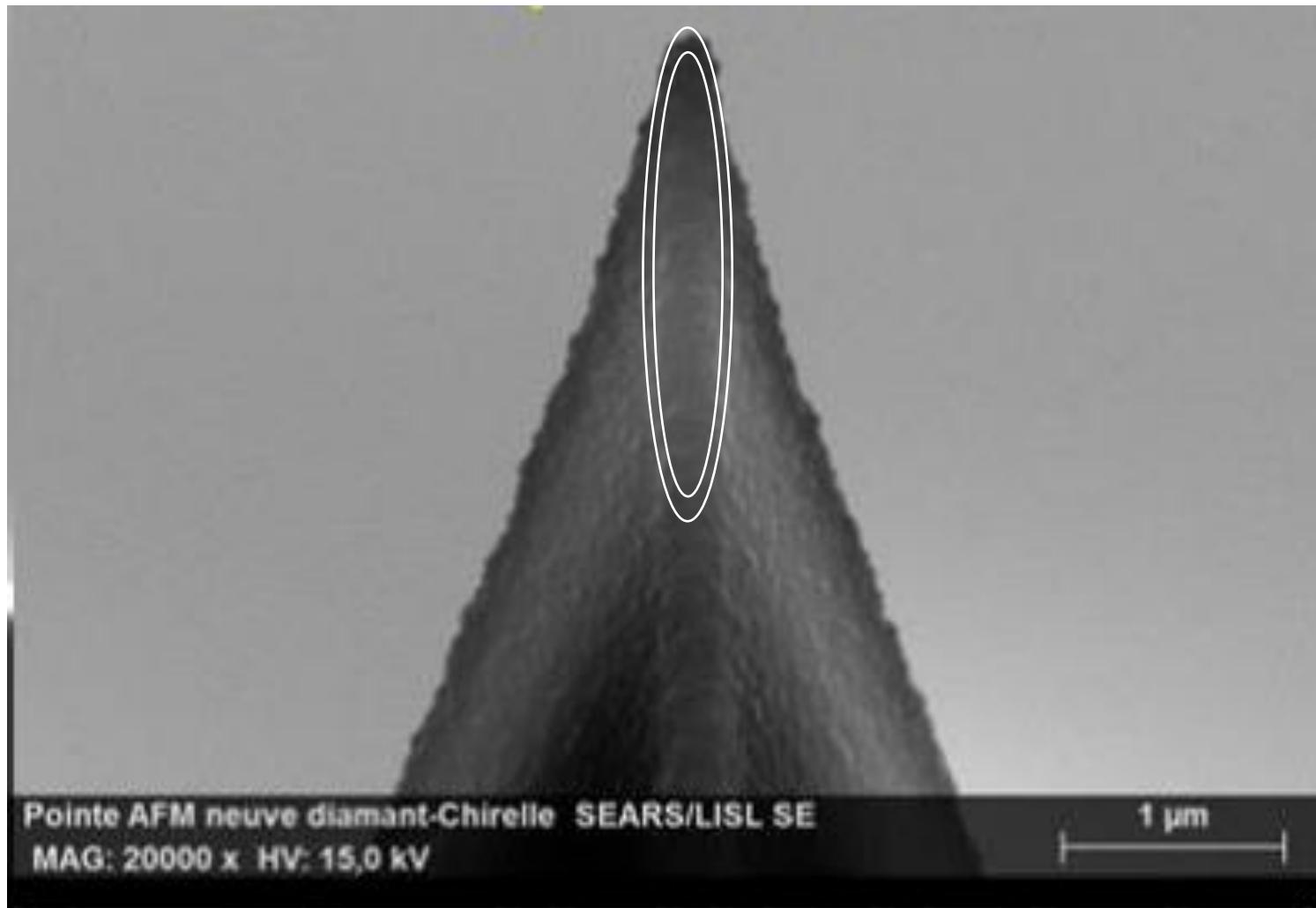
Q – from near-field calculation

$$\begin{aligned} k_i(T_b) \frac{\partial T_i(t, r, z)}{\partial z} \Big|_{z=z_{abl}(t, r)} &= \rho \Delta H V_{abl}(t, r), \\ \frac{\partial T_e(t, r, z)}{\partial z} \Big|_{z=z_{abl}(t, r)} &= 0. \end{aligned}$$

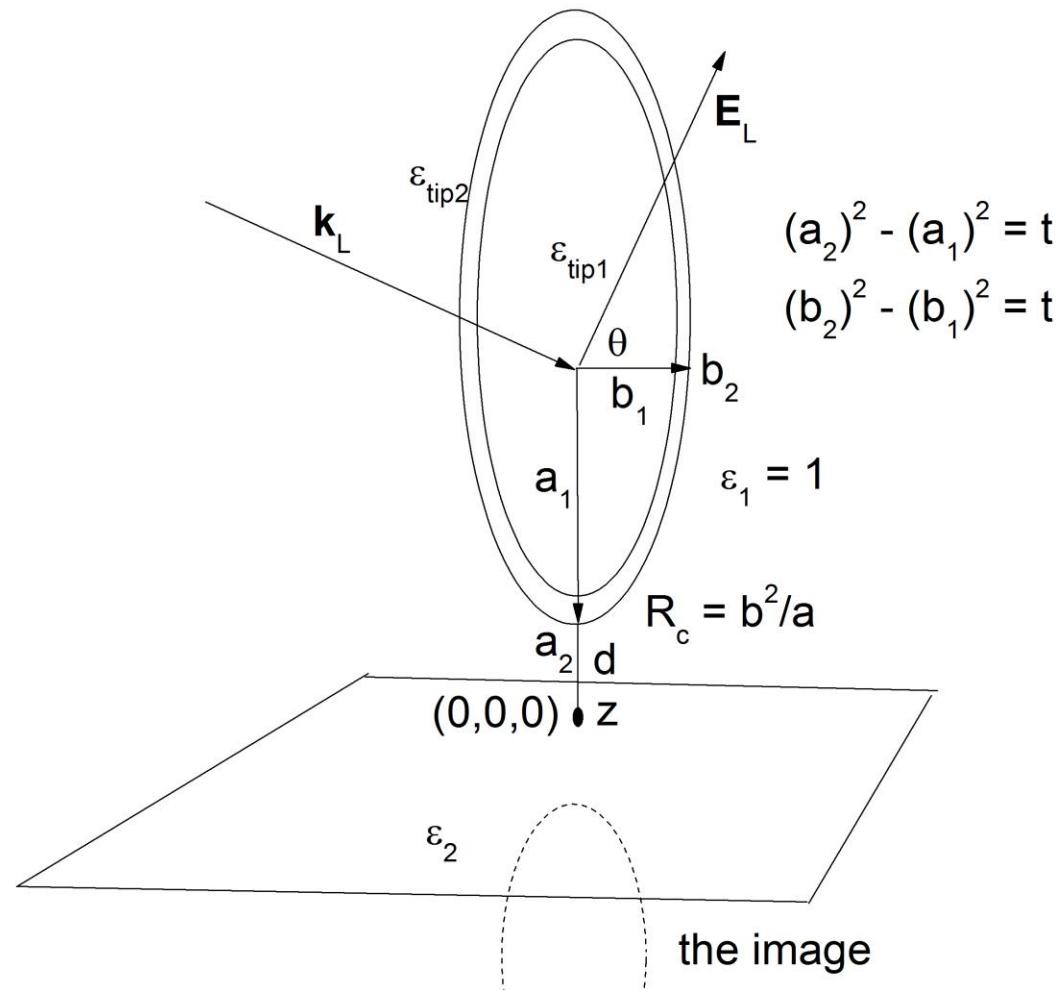
Si-tip of AFM with diamond cladding



Si-tip of AFM with diamond cladding



Near-field model for ellipsoidal tip with coating



Near-field model for ellipsoidal tip with coating (electrostatic approximation)

In the electrostatic approximation, the equations that describe the near electric field inside the medium under study (the medium 2) from the ellipsoid with a coating have the form:

$$E_x = -\frac{\partial \varphi}{\partial x}, \quad E_y = -\frac{\partial \varphi}{\partial y}, \quad E_z = -\frac{\partial \varphi}{\partial z},$$

$$\varphi(x, y, z) = -\frac{2E_L \sin \theta \Phi_a(x, y, z)}{1 + \varepsilon_2 + (1 - \varepsilon_2) \Phi'_{az}(0, 0, a_2 + d)},$$

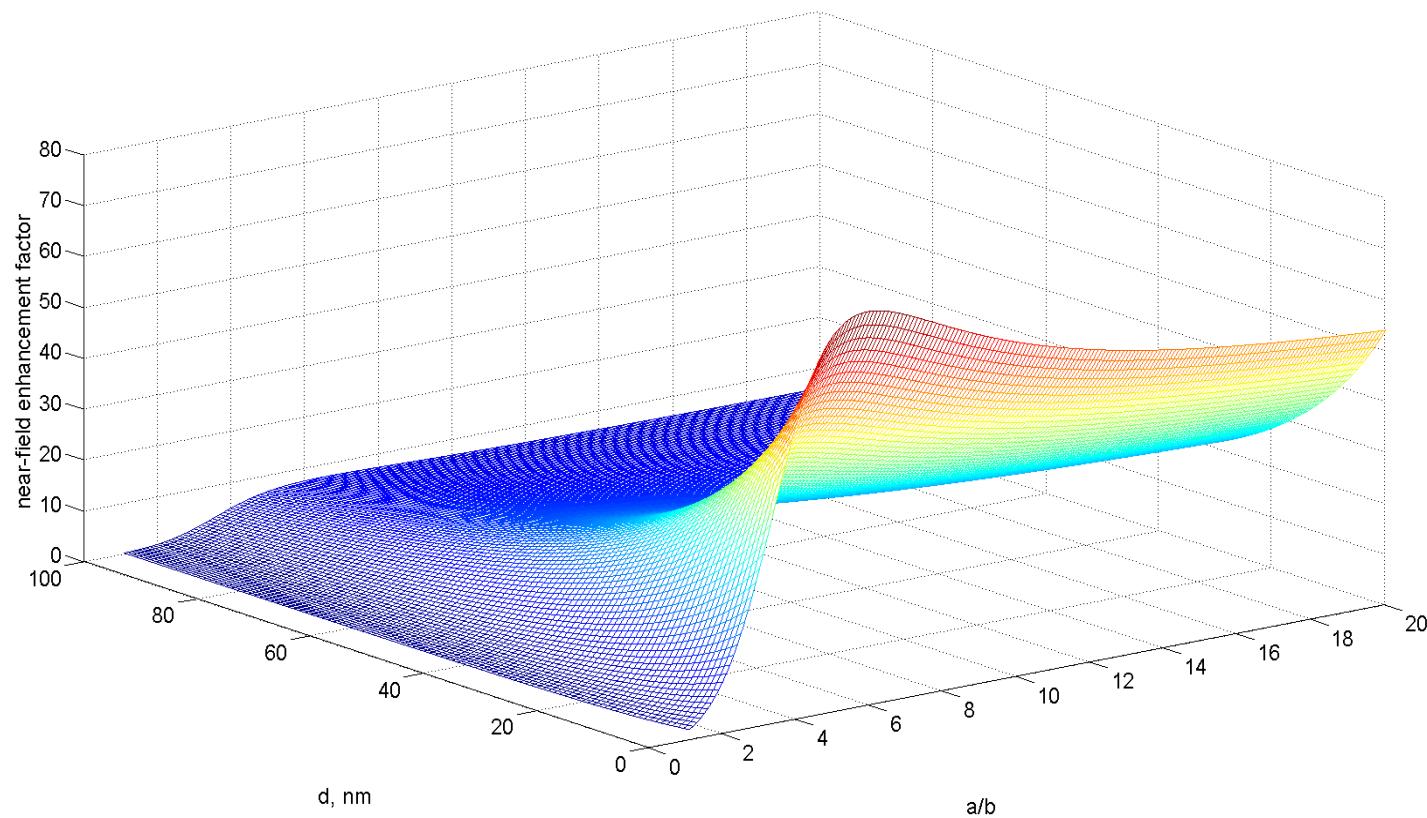
$$\Phi_a(x, y, z) = (z + a_2 + d) \frac{\frac{a_2 b_2^2}{2} (1 - Q) \int_{\xi}^{\infty} \frac{dq}{(b_1^2 + q)(a_1^2 + q)^{3/2}}}{1 - \frac{a_2 b_2^2}{2} (1 - Q) \int_t^{\infty} \frac{dq}{(b_1^2 + q)(a_1^2 + q)^{3/2}}},$$

$$Q = \frac{\varepsilon_{tip2} \left(\varepsilon_{tip2} + (\varepsilon_{tip1} - \varepsilon_{tip2}) \frac{a_1 b_1^2}{2} \int_0^t \frac{dq}{(b_1^2 + q)(a_1^2 + q)^{3/2}} + (\varepsilon_{tip1} - \varepsilon_{tip2}) \frac{a_1 b_1^2}{a_2 b_2^2} \right)}{\varepsilon_{tip2} + (\varepsilon_{tip1} - \varepsilon_{tip2}) \frac{a_1 b_1^2}{2} \int_0^t \frac{dq}{(b_1^2 + q)(a_1^2 + q)^{3/2}}},$$

$$\xi = \left(\frac{r_1 + r_2}{2} \right)^2 - a_1^2, \quad r_{1,2} = \sqrt{x^2 + y^2 + (z + a_2 + d \mp \sqrt{a_1^2 - b_1^2})^2}.$$

Near-field enhancement factor

$R_c = 100 \text{ nm}$, $\lambda = 266 \text{ nm}$, tip = Si+Diamond(0.3), medium = Au



Enhancement factors for the near-field for some cases as functions of a distance (d) of the tip from the surface and the tip aspect ratio (a/b).

BEM – Boundary Element Method

➤ **BEM-method:**

- is applied to solve the Maxwell equations for dielectric environment where bodies with homogeneous and isotropic dielectric functions are separated by abrupt interfaces;
- is suited, in principle, for arbitrary body sizes and photon energies;
- is best suited for metallic nanoparticles with the sizes from a few to a few hundreds of nanometers, and for frequencies in the optical and near-infrared regime;
- advantages: total surface utilisation = 2D-mesh of surfaces = rapid method / method for 3D-mesh

U. Hohenester and A. Trügler, *Comp. Phys. Commun.* **183**, 370 (2012)

U. Hohenester, *Comp. Phys. Commun.* **185**, 1177 (2014)

J. Waxenegger, A. Trügler, and U. Hohenester, *Comp. Phys. Commun.* **193**, 138 (2015)

➤ **MNPBEM** - a toolbox to provide a flexible simulation toolkit for calculation of electromagnetic properties of metallic nanoparticles (MNP) by BEM-method

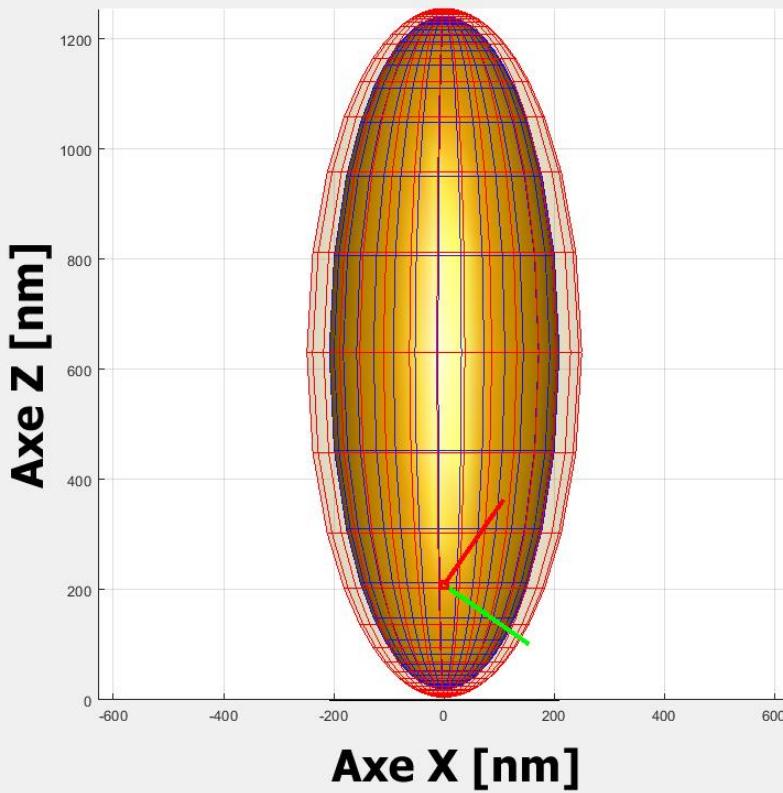
Current version **MNPBEM17**: developped by U. Hohenester and A. Trügler, University of Graz, Austria

Software implementation: MATLAB, version \geq R2015b

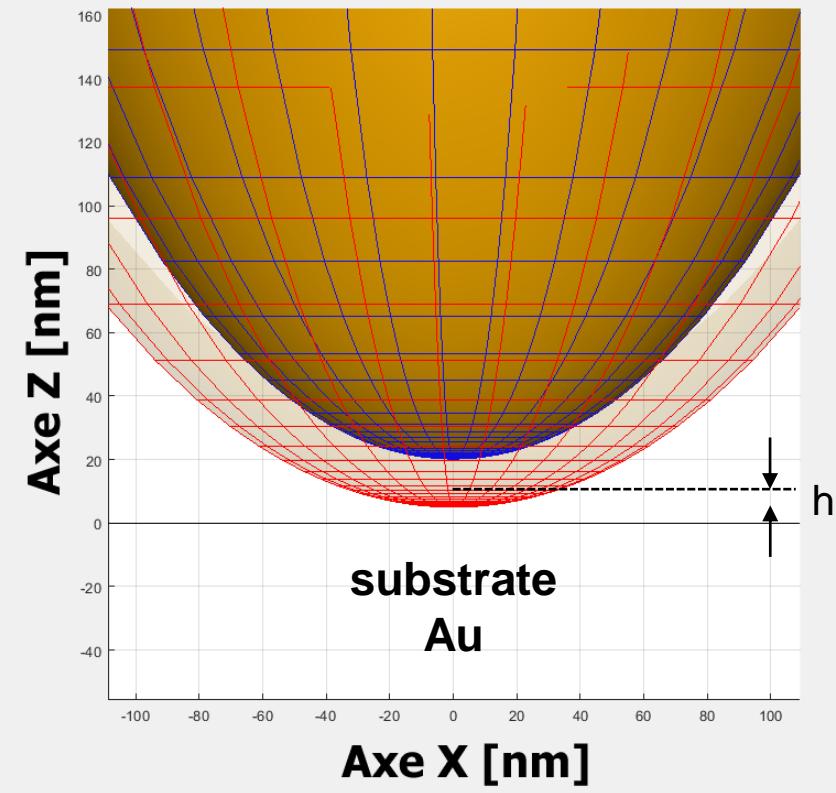
Download: <https://physik.uni-graz.at/mnpbem/>

BEM – Boundary Element Method

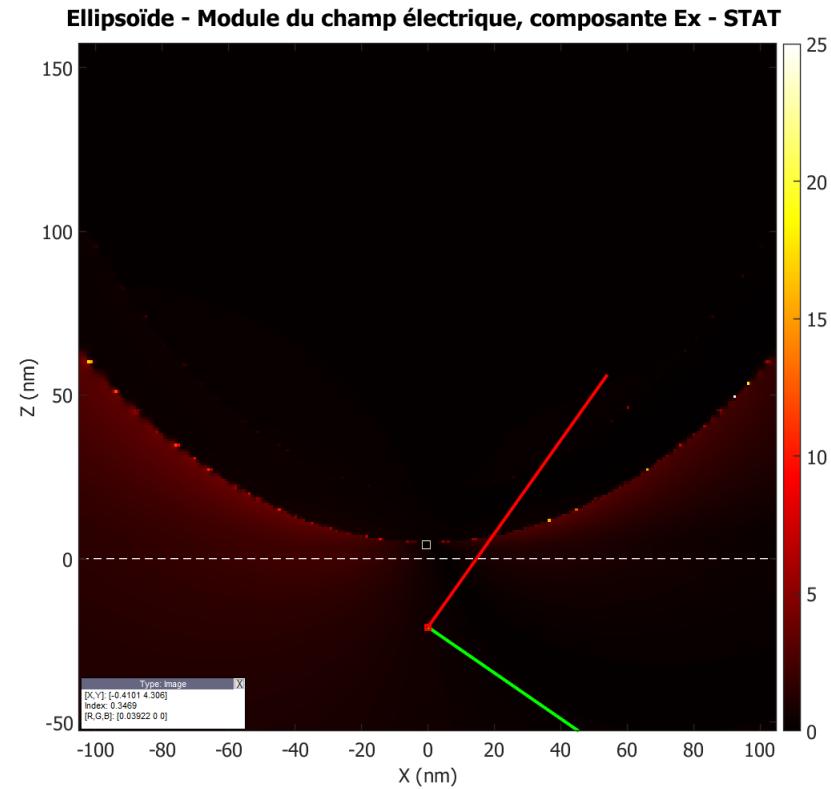
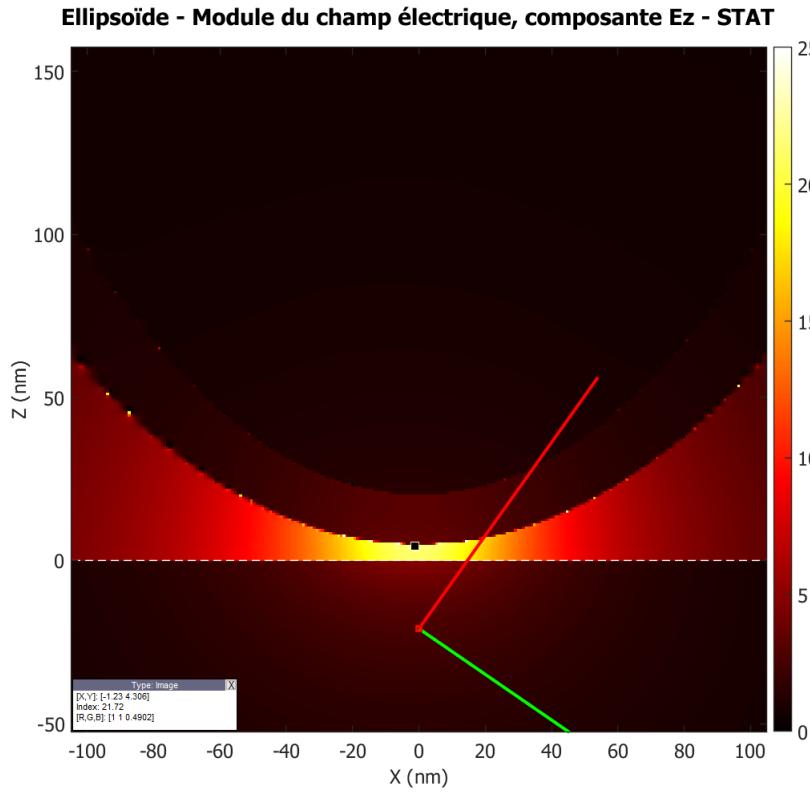
Géométrie Ellipsoïdes Concentriques



Geometrie Pointe

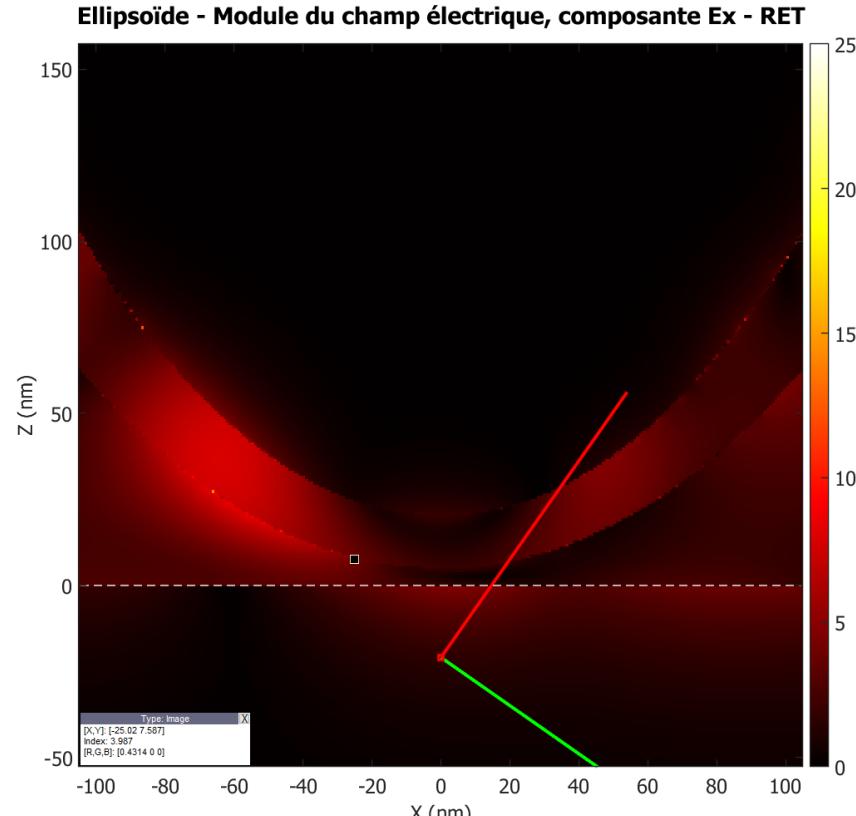
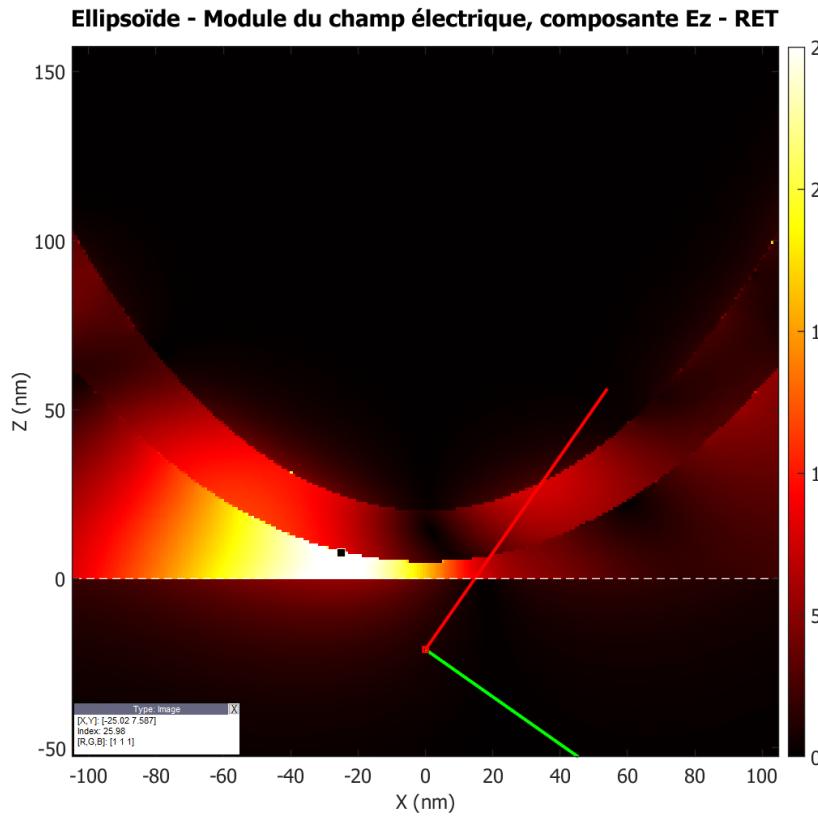


BEM simulation results (quasi-static approximation, 55° incidence)



- NF amplification factor for component $E_z \approx 22$

BEM simulation results (with light velocity delay, 55° incidence)

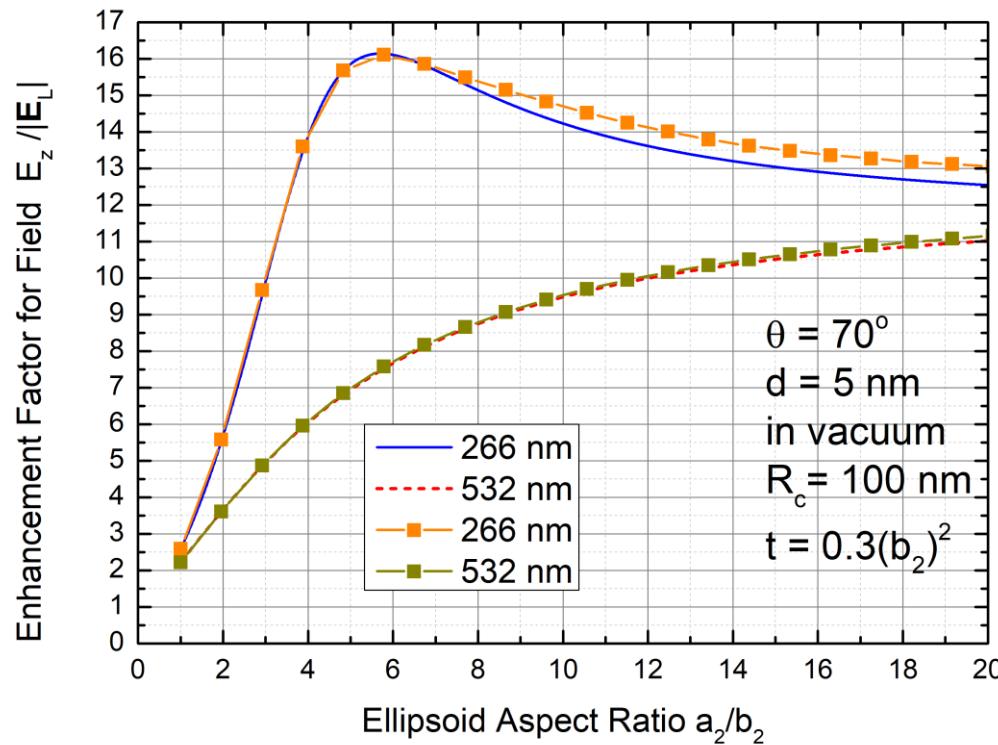


➤ NF amplification factor for component $E_z \approx 26$

Comparaison: analytical model and BEM simulations

E_z component evolution with a₂/b₂ aspect ratio

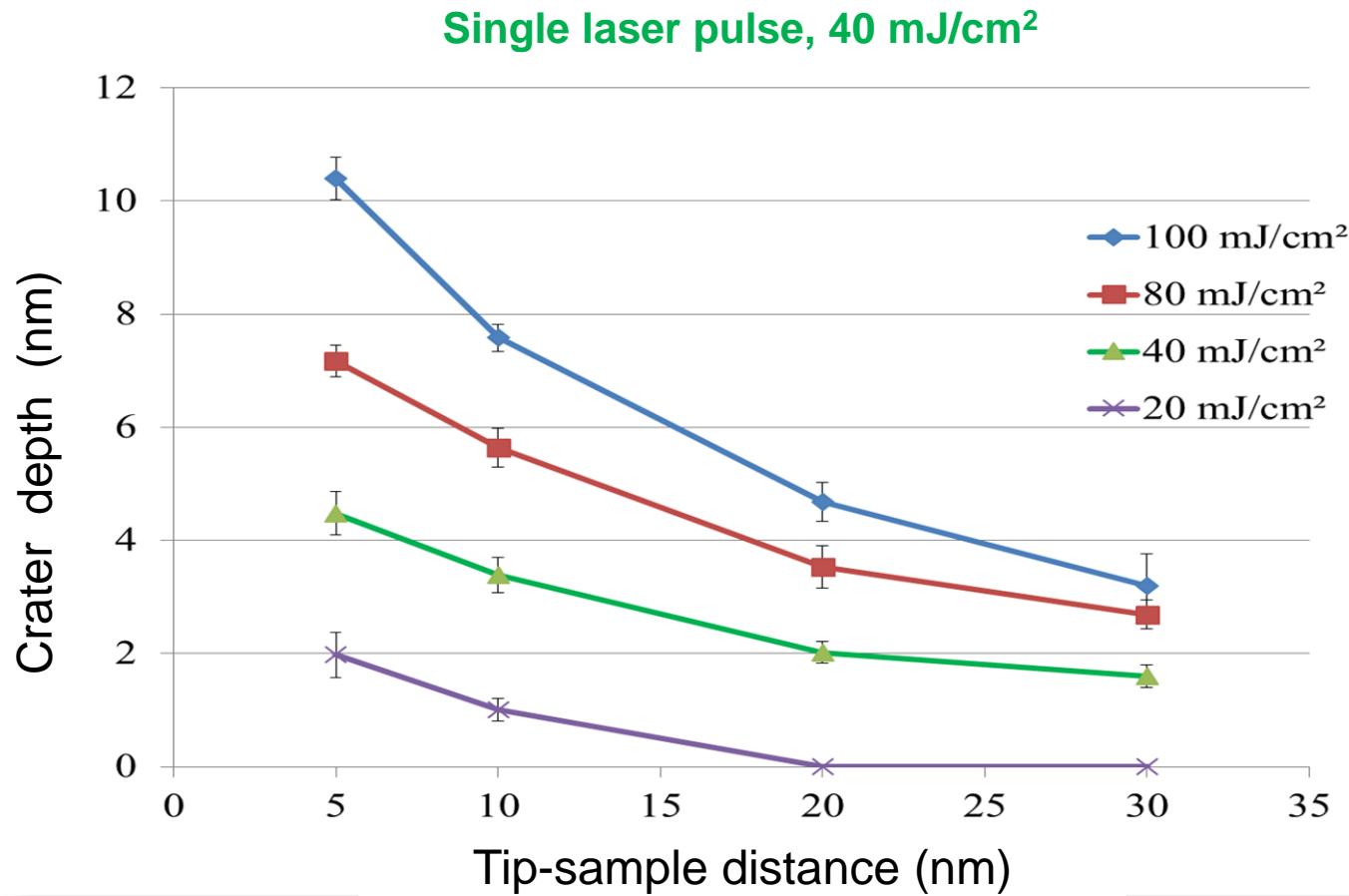
(without Au substrate, 266 nm and 532 nm wavelengths)



- Analytical model and BEM simulations are in **good agreement**.

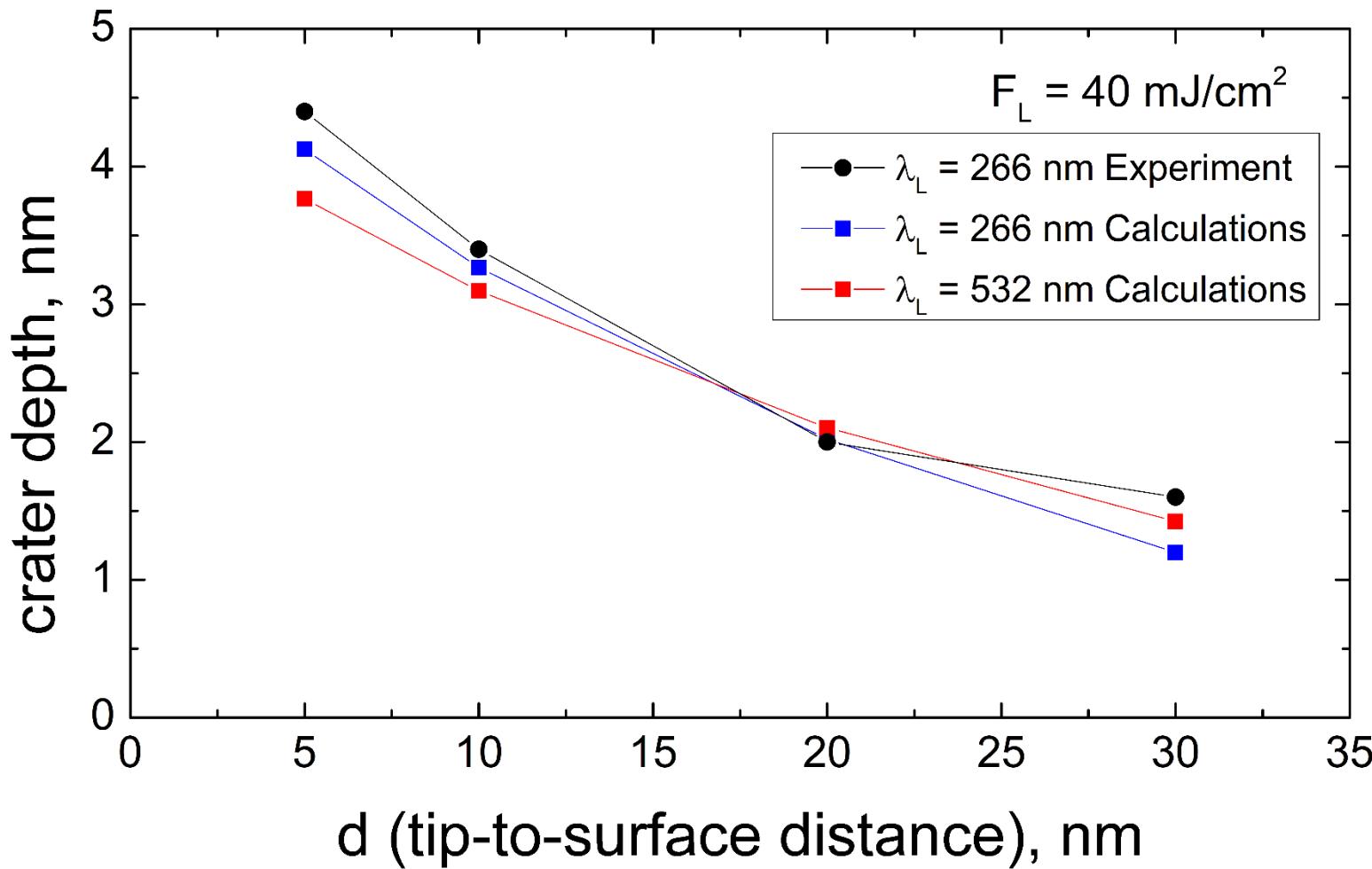
Experimental results (with Au)

Tip-sample distance and laser irradiance effects on the craters dimensions

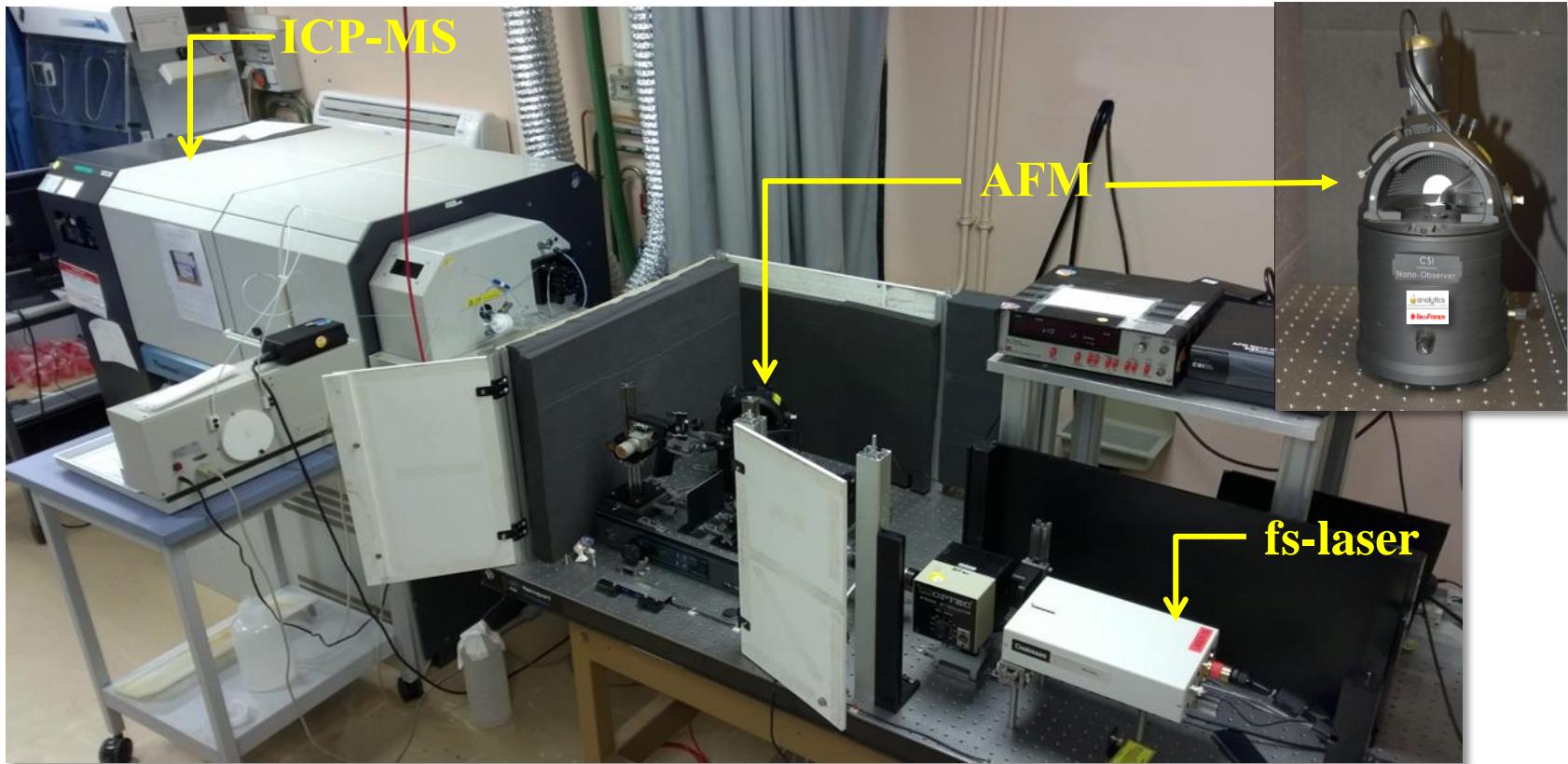


Simulation results (with Au)

Tip-sample distance effects on crater depth



PROSPECTS



- Laser Ti-Sa (800, 400 or 266 nm), 100 fs pulse duration.
- Development of NF-AFM interface with ICP-MS (on-going).
- Particle characterization: particle size, mass, shape ... (on-going).
- Element and isotope analysis by NF-AFM-ICP-MS.

Спасибо
за
внимание!

Thank you
for your
attention!

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685 019

DEN-DANS
DPC
SEARS

➤ Champ électrique sur une surface métallique - Equation de Fresnel généralisée - Indice de réfraction complexe

$$(\vec{E}_x^{Exc.}, \vec{E}_y^{Exc.}, \vec{E}_z^{Exc.}) = E_0((r_{//} - 1) \cos \alpha \cdot \cos \theta, (1 + r_{\perp}) \sin \theta, (1 + r_{//}) \sin \alpha \cdot \cos \theta)$$

α Angle d'incidence / normale

θ Angle de polarisation

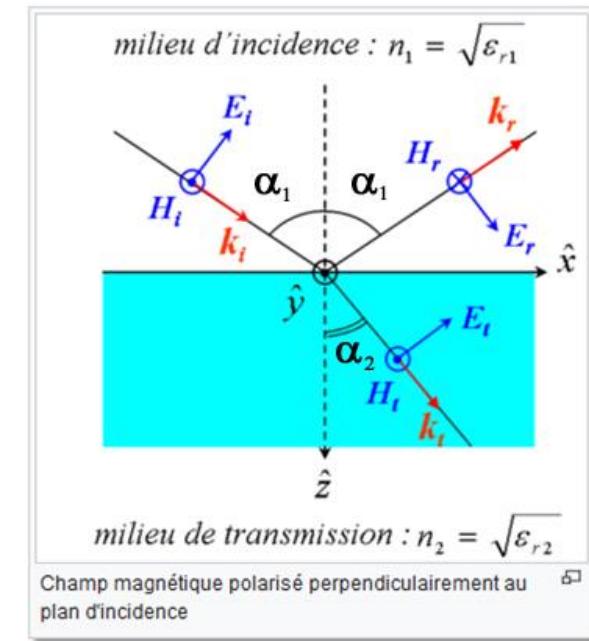
$r_{//} = r_{TM}$ Coefficient de Fresnel en polarisation TM

$r_{\perp} = r_{TE}$ Coefficient de Fresnel en polarisation TE

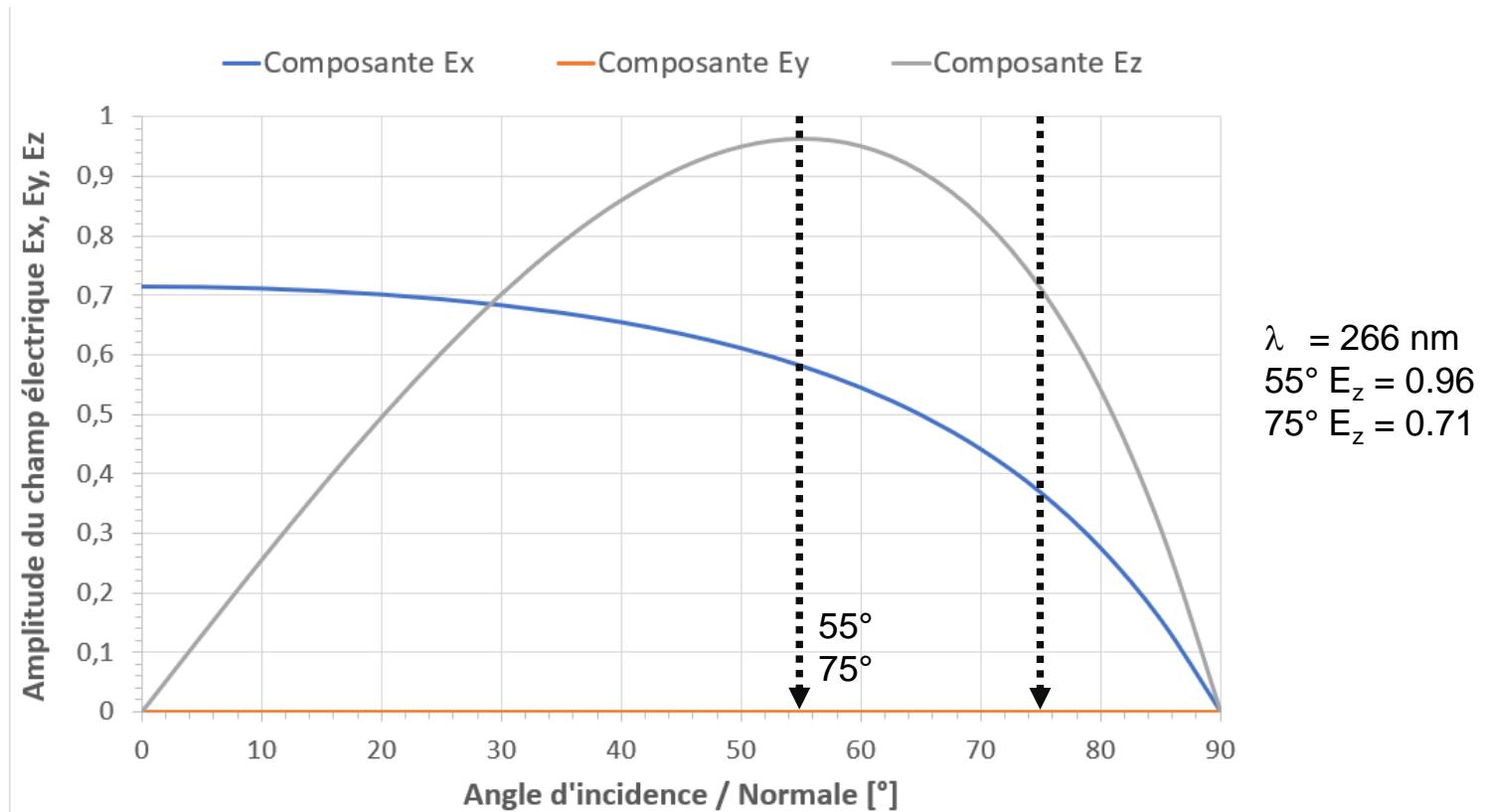
$$r_{//} = \frac{n_2^2 \cos(\theta) - n_1 \sqrt{n_2^2 - n_1^2 \sin^2(\theta)}}{n_2^2 \cos(\theta) + n_1 \sqrt{n_2^2 - n_1^2 \sin^2(\theta)}}$$

$$r_{\perp} = \frac{n_1 \cos(\theta) - \sqrt{n_2^2 - n_1^2 \sin^2(\theta)}}{n_1 \cos(\theta) + \sqrt{n_2^2 - n_1^2 \sin^2(\theta)}}$$

avec $n = n_1 + i \cdot n_2$ Indice de réfraction complexe du substrat métallique



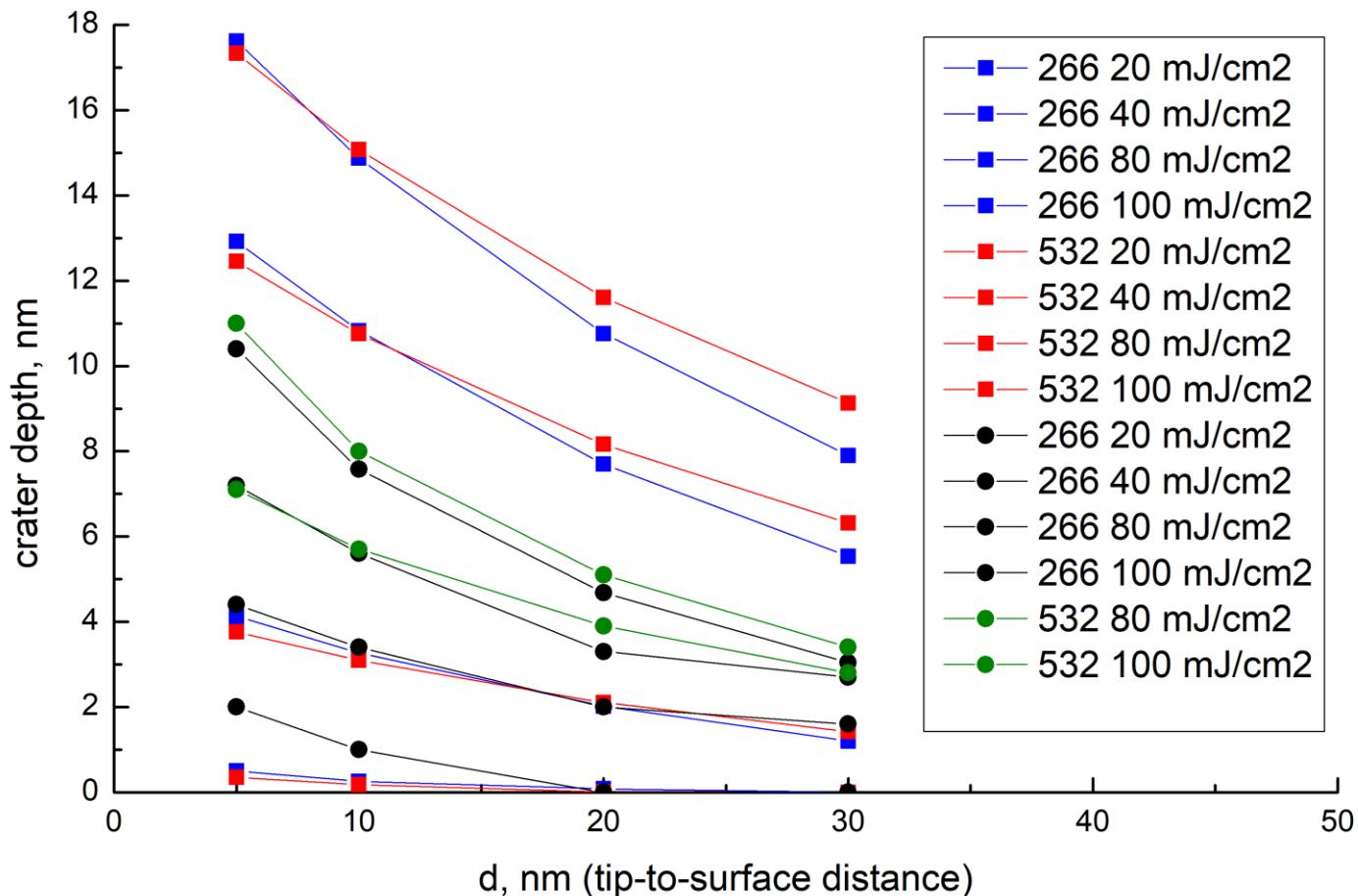
BEM - Géométrie d'illumination optimale - Théorie de Fresnel



- Maximisation de la composante E_z pour un angle d'illumination de 55° / normale

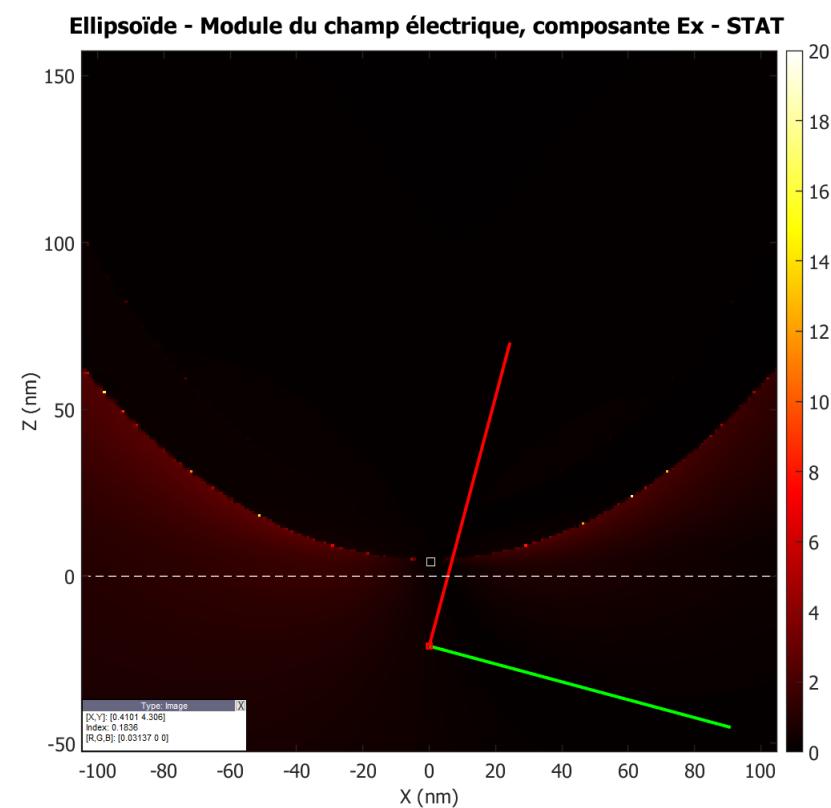
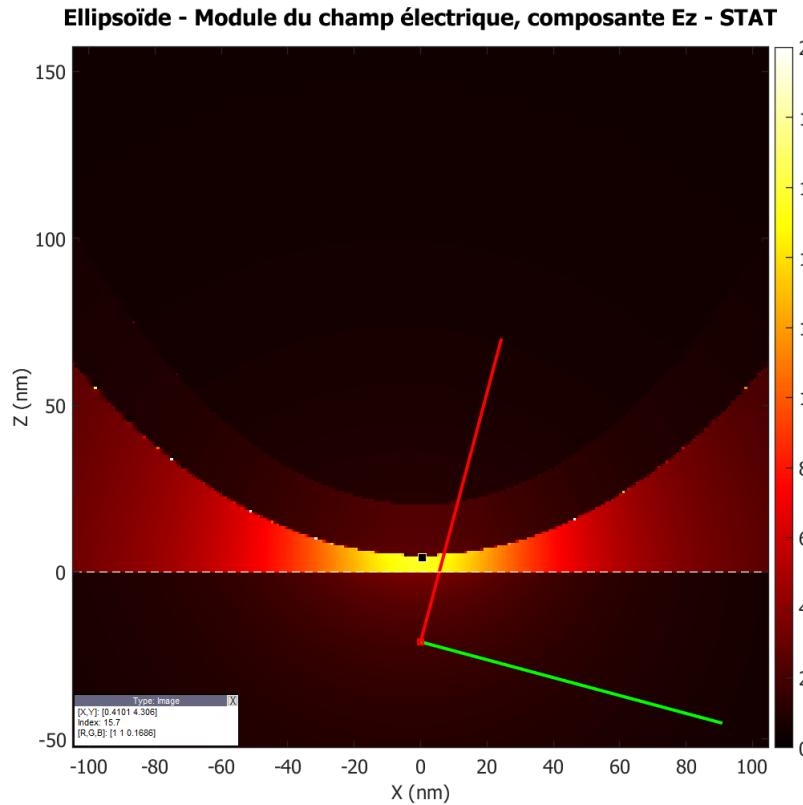
EXPERIMENTAL RESULTS

Tip-sample distance and laser irradiance effects on craters dimensions



BEM results with quasi-static approximation

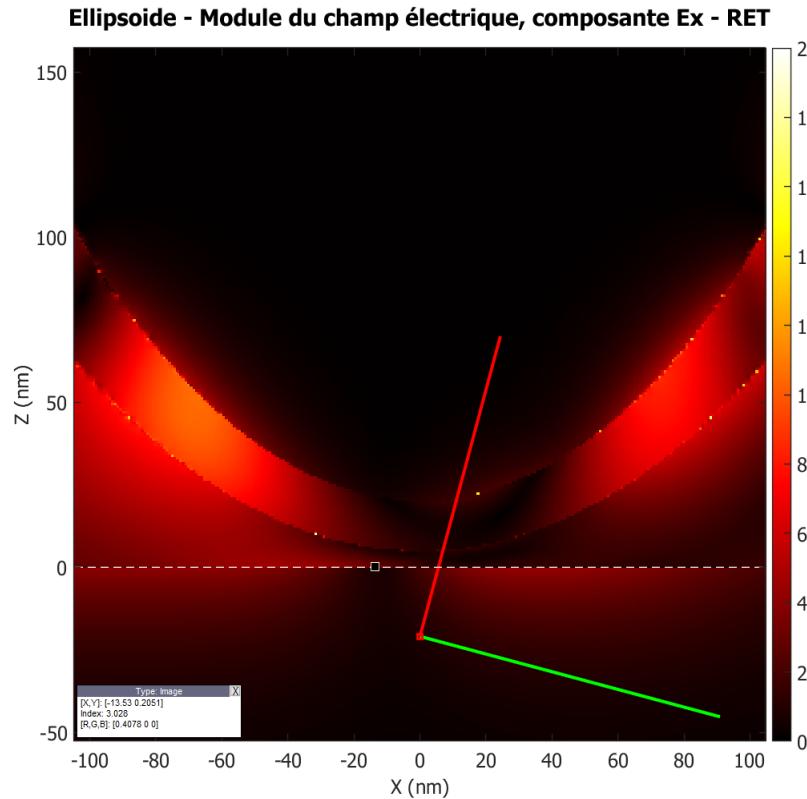
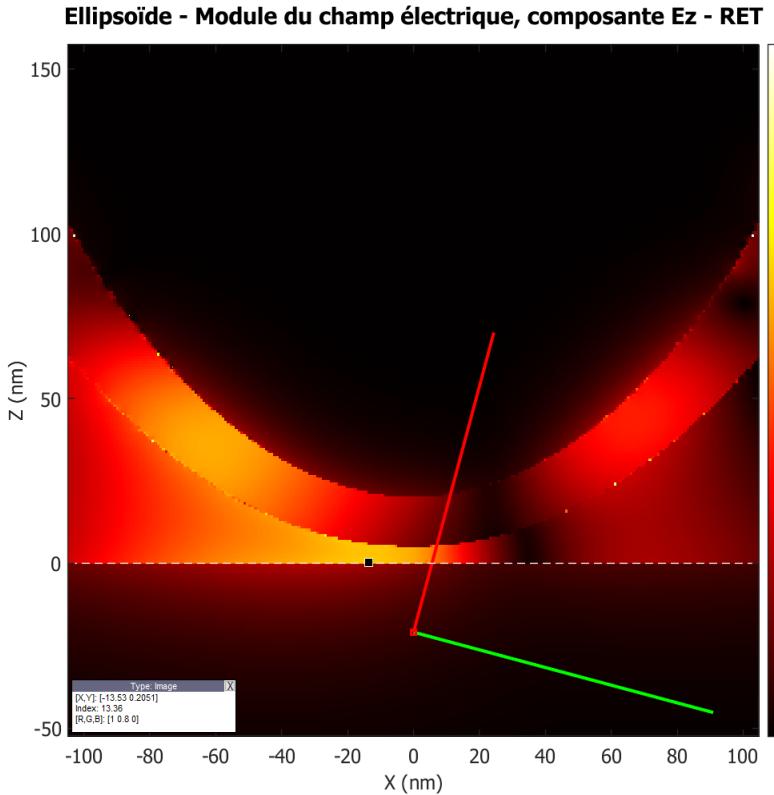
Incidence 75°



➤ Facteur d'exaltation de la composante $E_z \approx 16$

BEM results with light velocity effect

Incidence 75°



➤ Facteur d'exaltation de la composante $E_z \approx 13$

BEM results

BEM results simulation – electric field profile (suivant l'axe de la pointe – 75°)

